





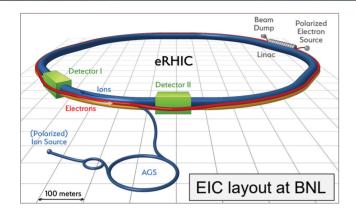
Progress towards long lifetime high current polarized electron sources

Jyoti Biswas

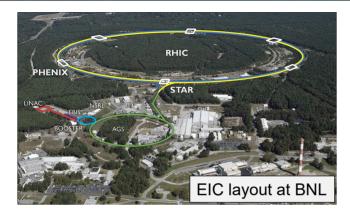
Brookhaven National Laboratory On behalf of the collaborations August 9, 2022



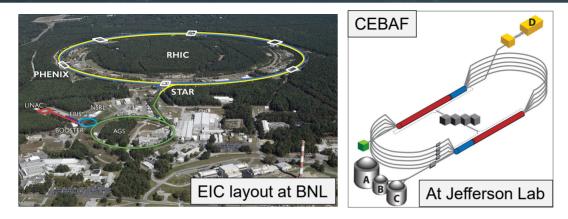




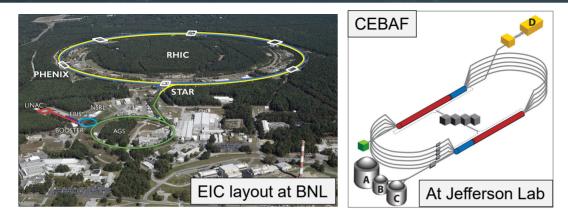


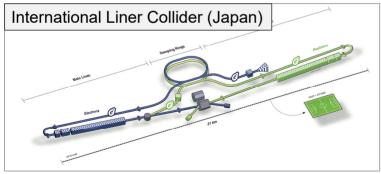




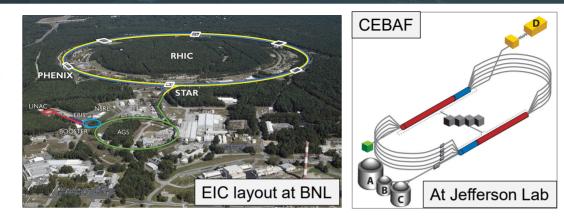


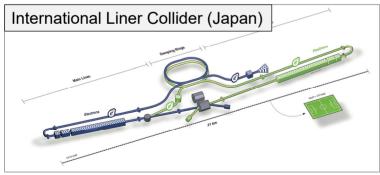


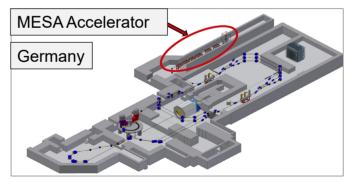




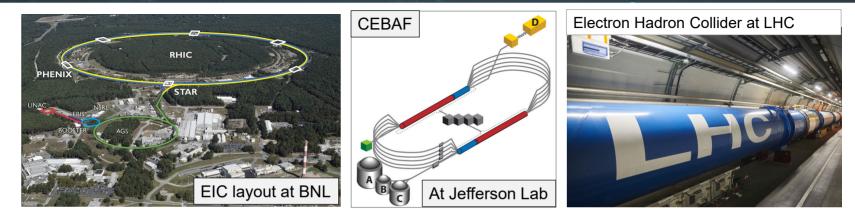


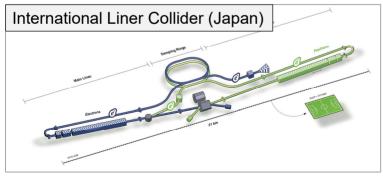


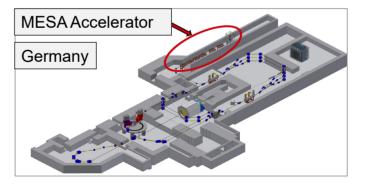








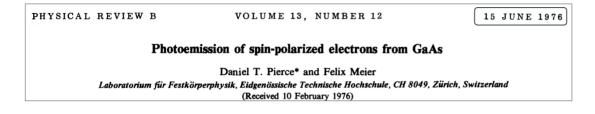




GaAs-based photocathodes



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GaAs-based photocathodes

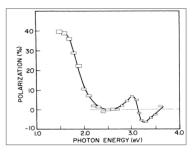
PHYSICAL REVIEW B

VOLUME 13, NUMBER 12

15 JUNE 1976

Photoemission of spin-polarized electrons from GaAs

Daniel T. Pierce^{*} and Felix Meier Laboratorium für Festkörperphysik, Eidgenössische Technische Hochschule, CH 8049, Zürich, Switzerland (Received 10 February 1976)





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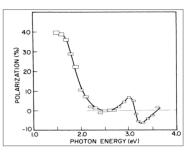
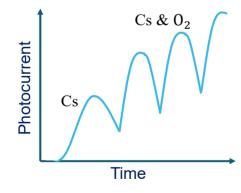


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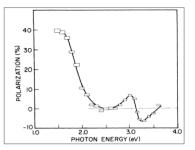
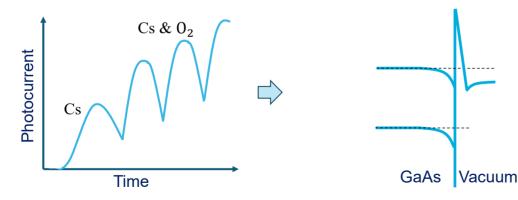


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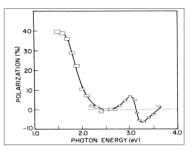
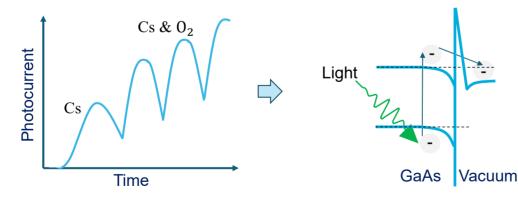


Photo-Emission from GaAs





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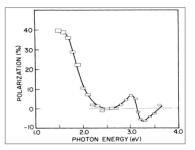
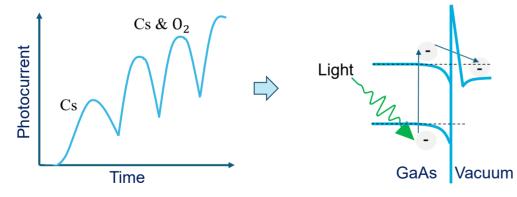
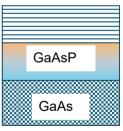


Photo-Emission from GaAs





Superlattice GaAs ESP~92% (@780nm) QE~1.6% (@780nm)



GaAs-based photocathodes: Essential Attributes



GaAs-based photocathodes: Essential Attributes

High Quantum Efficiency (QE)

Long charge lifetime

High Electron Spin Polarization (ESP)



GaAs-based photocathodes: Essential Attributes

High Quantum Efficiency (QE)

- Reducing Surface Contamination
- → Engineering the cathode, SL-DBR
- → Robust activation layer material

Long charge lifetime

High Electron Spin Polarization (ESP)



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SL-GaAs, or SL-DBR



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High Electron Spin Polarization (ESP)

SL-GaAs, or SL-DBR



I will present our advances on each of these issues!

Motivation:

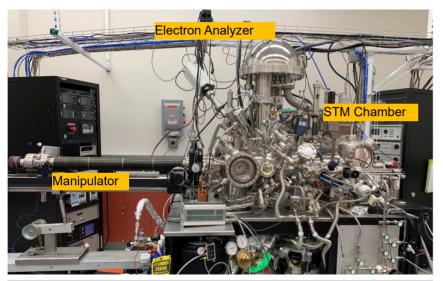
Understanding surface roughness variations due to heat treatment

□ Understanding surface cleaning and its effect on QE

Evaluating chemical states of CsO/GaAs



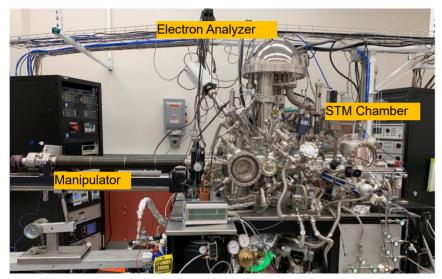
Substrate Preparation and Characterization

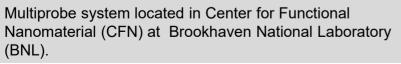


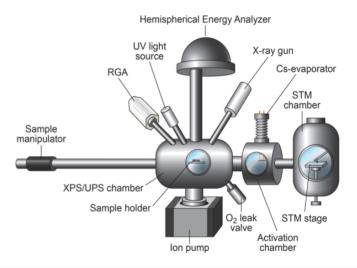
Multiprobe system located in Center for Functional Nanomaterial (CFN) at Brookhaven National Laboratory (BNL).



Substrate Preparation and Characterization







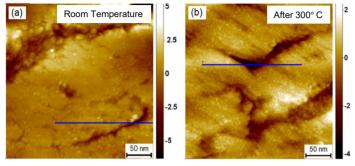
Schematic drawing of the multiprobe system at CFN, BNL



Substrate Preparation and Characterization - Surface Roughness



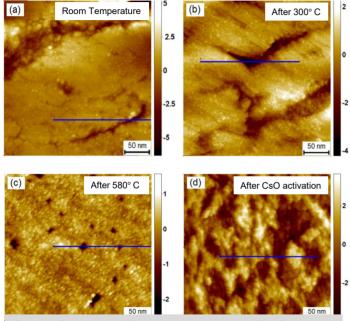
Substrate Preparation and Characterization - Surface Roughness



STM - GaAs at different temperature, & after activation



Substrate Preparation and Characterization - Surface Roughness

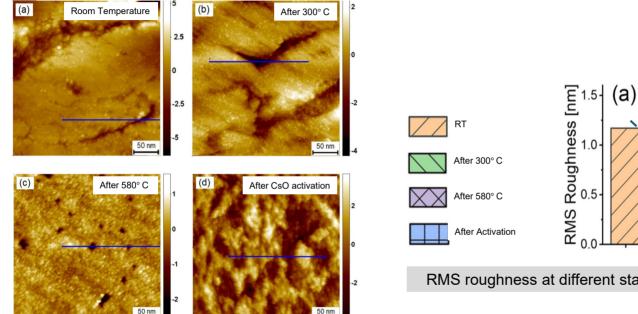


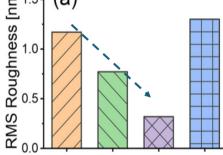
STM - GaAs at different temperature, & after activation



J. Biswas et al. J. Appl. Phys. 128, 045308 (2020); https://doi.org/10.1063/5.0008969

Substrate Preparation and Characterization - Surface Roughness





RMS roughness at different stage of the activation

STM - GaAs at different temperature, & after activation



J. Biswas et al. J. Appl. Phys. 128, 045308 (2020); https://doi.org/10.1063/5.0008969

Conclusion from Substrate Preparation and Characterization



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□ Contrary to common assumption, we found that right amount of heat treatment at UHV decreases the surface RMS roughness.



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This preparation is optimal for the subsequent growth of thin activation material on it.



Conclusion from Substrate Preparation and Characterization

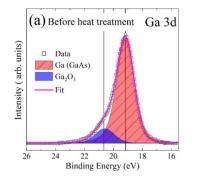
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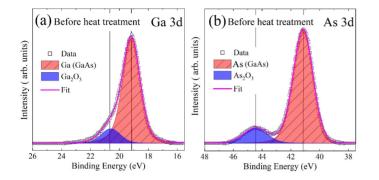
Reduced field emission and emittance growth.



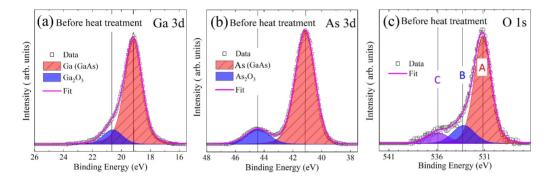




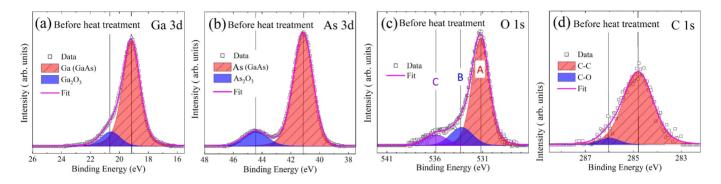






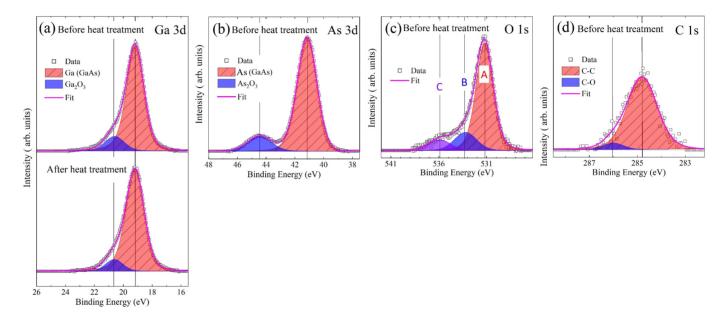






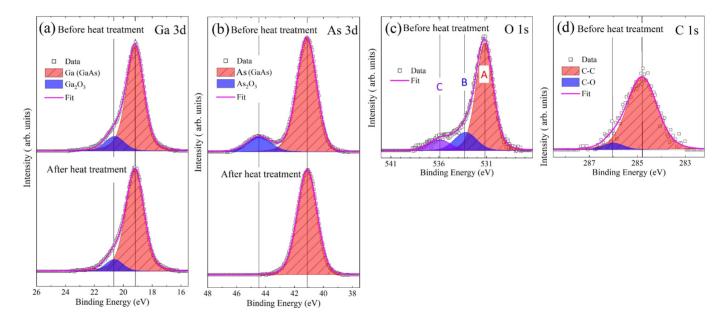


Pre-growth contamination analysis using XPS



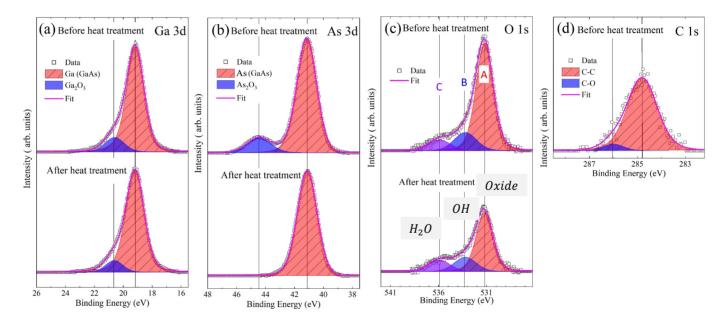


Pre-growth contamination analysis using XPS



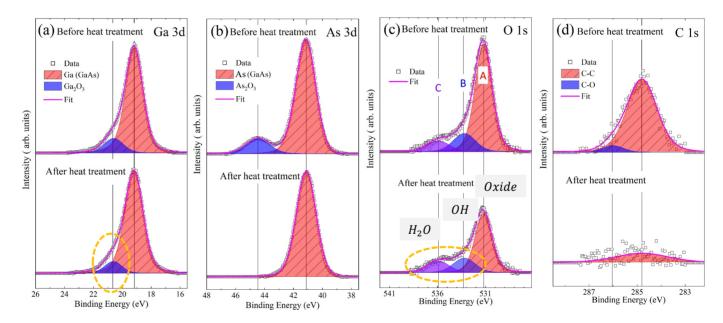


Pre-growth contamination analysis using XPS





Pre-growth contamination analysis using XPS





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Conclusion from pre-growth contamination analysis



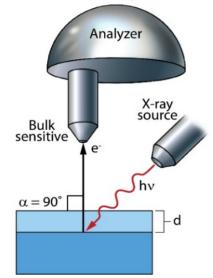
Conclusion from pre-growth contamination analysis

Although others have confirmed that presence of H_20 leads to lower QE, we have shown presence of H_20 causes other types of contamination to appear on the surface.



Chemical analysis of CsO/GaAs cathode using AR-XPS/UPS

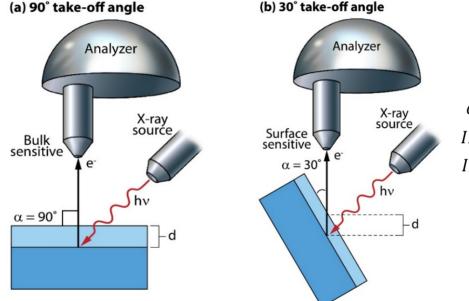
(a) 90° take-off angle



 $\alpha = electron \ take \ off \ angle$ $ID = Information \ depth$ $ID = d \ sin \alpha$



Chemical analysis of CsO/GaAs cathode using AR-XPS/UPS



 $\alpha = electron \ take \ off \ angle$ $ID = Information \ depth$ $ID = d \ sin \alpha$

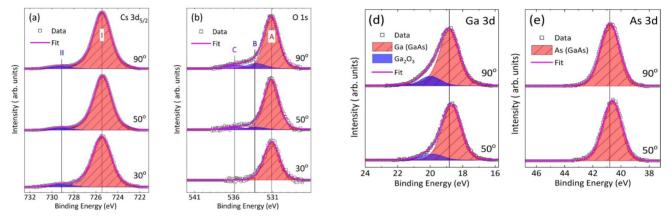


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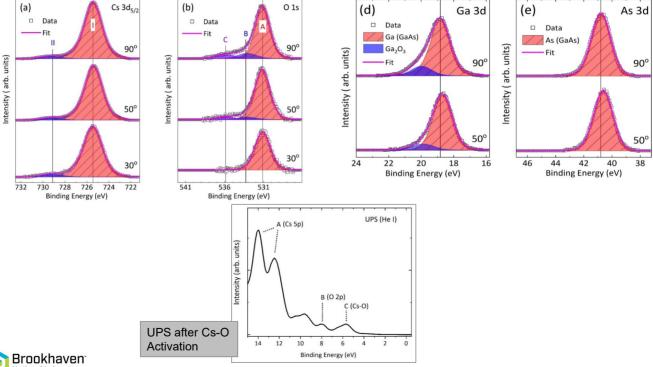


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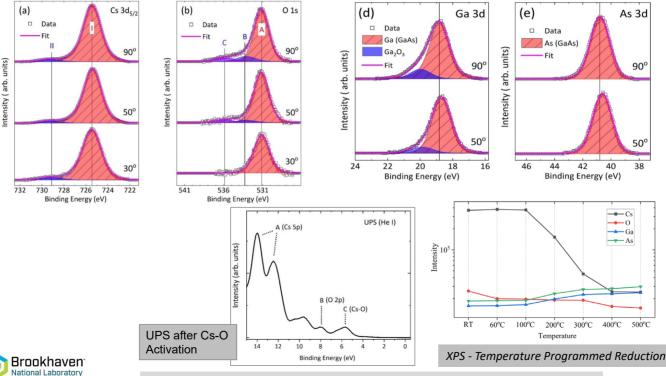


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Conclusion from the chemical analysis of CsO/GaAs



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Conclusion from the chemical analysis of CsO/GaAs

□ This is a **first detailed chemical analysis** of Cs-O activation on GaAs.



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 \Box We find the ratio of Cs & O on the activation layer, Cs:O \approx 2:1

> No formation of previously proposed Cs_20 , or $Cs_{11}0_3$ compound in activation layer.



Conclusion from the chemical analysis of CsO/GaAs

□ This is a **first detailed chemical analysis** of Cs-O activation on GaAs.

❑ We find the ratio of Cs & O on the activation layer, Cs:O ≈ 2:1
➢ No formation of previously proposed Cs₂O, or Cs₁₁O₃ compound in activation layer.

□ XPS confirms that, surface start to lose Cs significantly at ~100°C, whereas **oxygen loss is significant even at 60°C**.

Laser illumination induced heating could destroy the cathode if temperature of the sample exceeds 60°C.



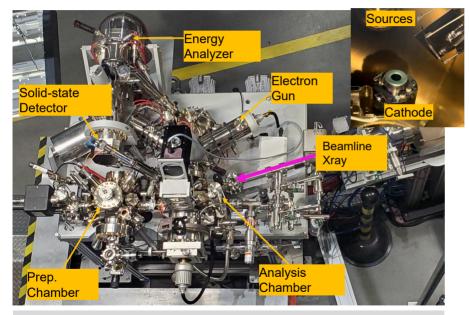
New Activation Technique using Te, Cs, and O

We developed a new technique of activation employing a combination of cesium, tellurium, and oxygen that shows longer charge lifetime.





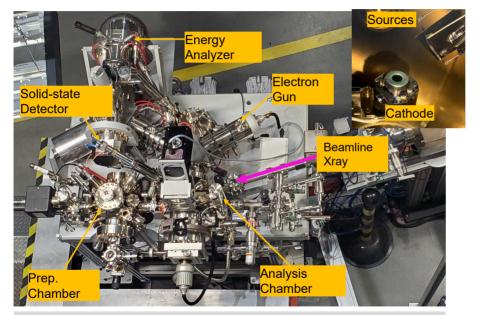
New Cs-Te and Cs-Te-O based Activation on GaAs



LEEM/XPEEM beamline located at NSLS II, BNL



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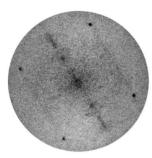


Cathode chamber at CAD, BNL





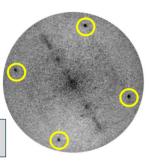
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Oxide desorption – LEED



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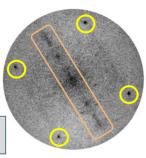


(1x1), & defused (4x6) reconstruction

Oxide desorption – LEED



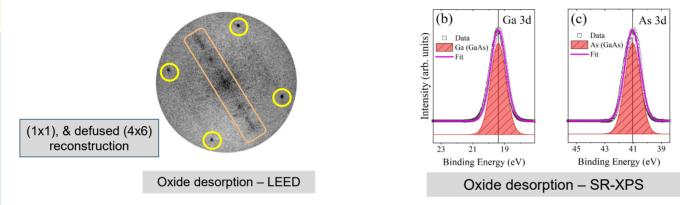
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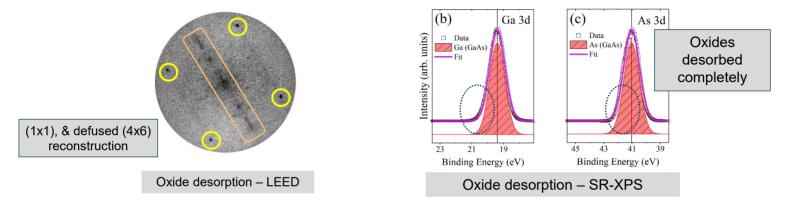
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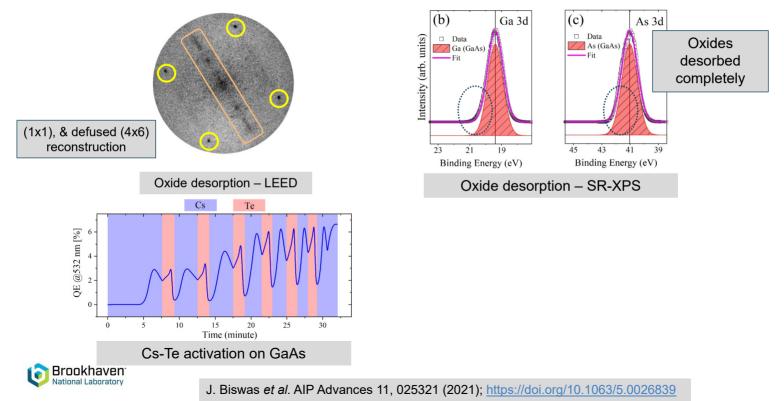




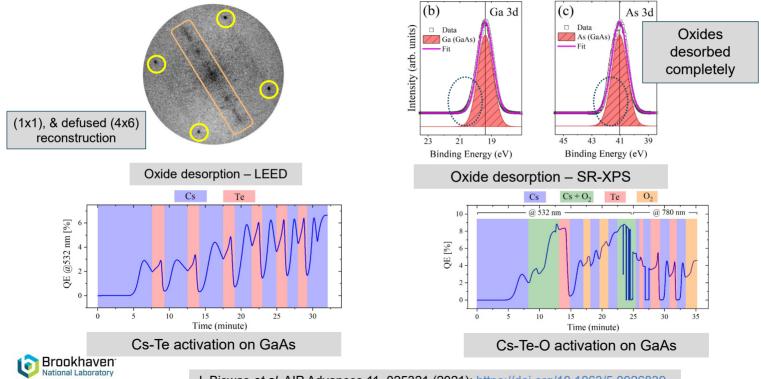








New Cs-Te and Cs-Te-O based Activation on GaAs



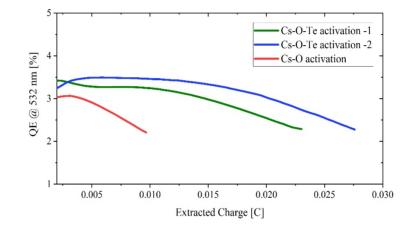
Conclusion from the Cs-Te and Cs-Te-O based Activation

□ In Cs-Te activation QE at 532 nm: 6.6%

In Cs-Te-O activation QE at 532 nm: 8.8%; at 780 nm: 4.5%



Comparing Charge lifetime of Cs-Te-O based Activation



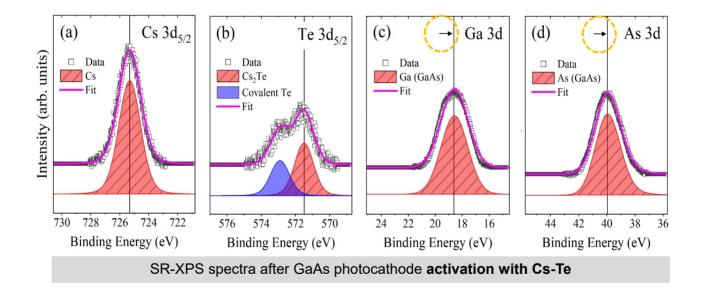
We demonstrated 5-6 times longer charge lifetime in a test chamber as compared to Cs-O/GaAs



Evaluating Surface Chemical States Cs-Te/GaAs



Evaluating Surface Chemical States Cs-Te/GaAs





Conclusion from Surface Chemical States Cs-Te/GaAs



Conclusion from Surface Chemical States Cs-Te/GaAs

□ Successful formation of Cs_2Te , which is robust against poor vacuum



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Chemical shift of Ga 3d, & As 3d suggest formation of surface dipole, similar to Cs-O activation.



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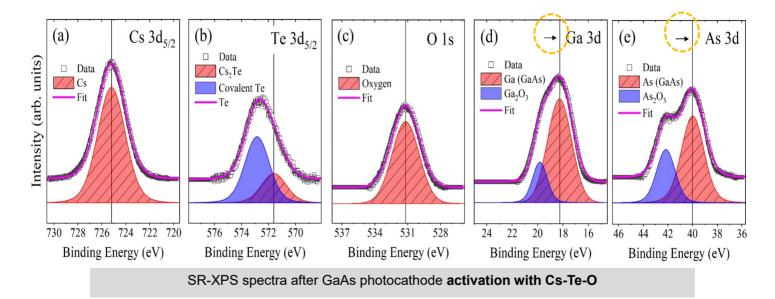
 \Box Estimated Cs-Te layer thickness $2 \pm 0.2 nm$



Evaluating Surface Chemical States Cs-Te-O/GaAs



Evaluating Surface Chemical States Cs-Te-O/GaAs





J. Biswas et al. AIP Advances 11, 025321 (2021); https://doi.org/10.1063/5.0026839

Conclusion from the Chemical Analysis of Cs-Te-O/GaAs



Conclusion from the Chemical Analysis of Cs-Te-O/GaAs

□ Successful formation of Cs_2Te , which is robust against poor vacuum



Conclusion from the Chemical Analysis of Cs-Te-O/GaAs

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Conclusion from the Chemical Analysis of Cs-Te-O/GaAs

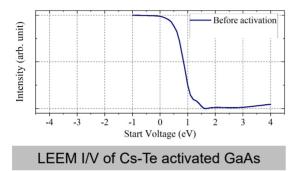
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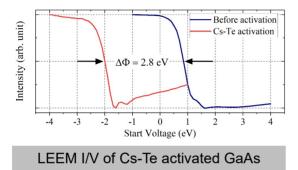
 \Box Estimated Cs-Te layer thickness $1.6 \pm 0.2 nm$



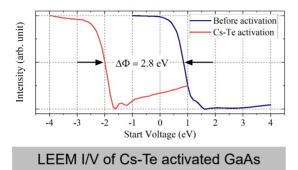


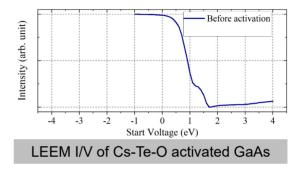




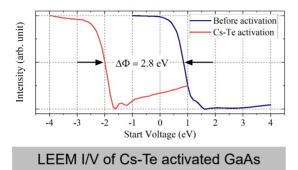


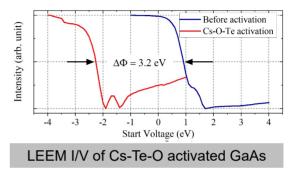






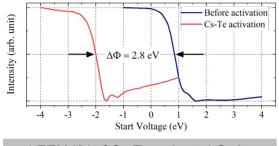




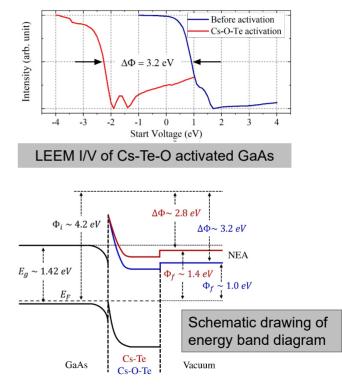




Evaluating the Negative Electron Affinity (NEA)

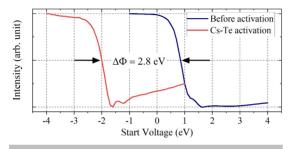


LEEM I/V of Cs-Te activated GaAs





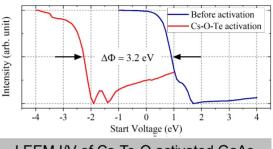
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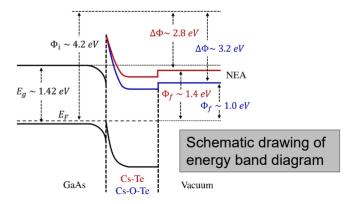
LEEM I/V of Cs-Te activated GaAs

Cs-Te/GaAs

Final work function, $\Phi_f = 1.4 \text{ eV}$ Effective NEA, $\chi_{eff} = -0.02 \text{ eV}$

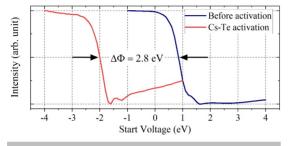


LEEM I/V of Cs-Te-O activated GaAs





Evaluating the Negative Electron Affinity (NEA)



LEEM I/V of Cs-Te activated GaAs

Cs-Te/GaAs

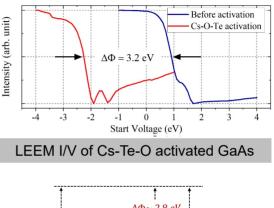
Final work function, $\Phi_f = 1.4 \text{ eV}$

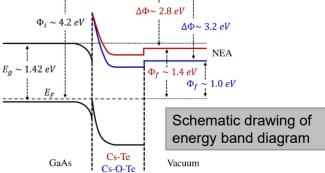
Effective NEA, $\chi_{eff} = -0.02 \text{ eV}$

Cs-Te-O/GaAs

Final work function, $\Phi_f = 1.0 \text{ eV}$ Effective NEA, $\chi_{eff} = -0.42 \text{ eV}$







J. Biswas et al. AIP Advances 11, 025321 (2021); https://doi.org/10.1063/5.0026839

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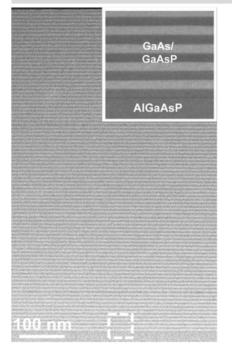
NEA is important because the thermalized electrons at the bottom of the conduction band can escape into the vacuum. Thus, QE increases the when larger NEA is achieved.



Superlattice (SL) GaAs

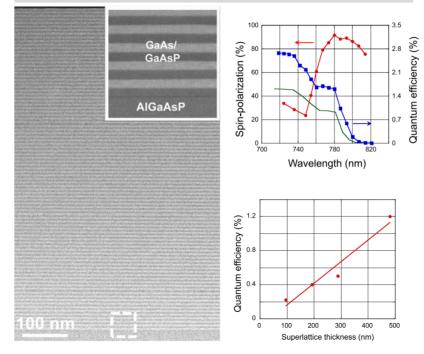


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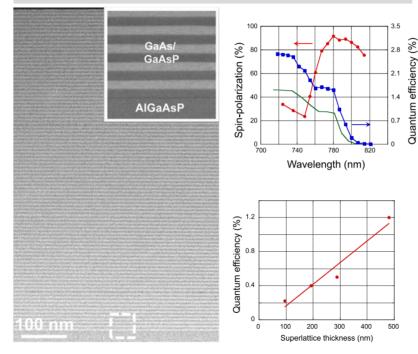
Superlattice (SL) GaAs





Jin et el. Appl. Phys. Lett. 105, 203509 (2014)

Superlattice (SL) GaAs



SL – GaAs with Bragg Reflector



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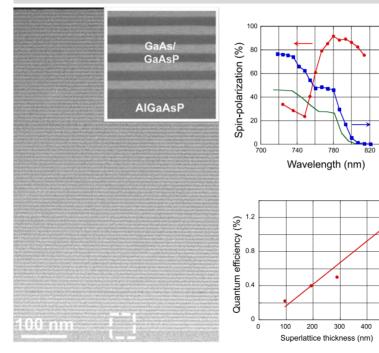
Quantum efficiency (%)

2.8

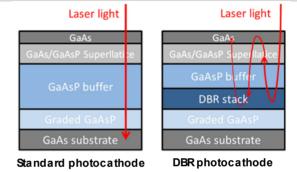
07

500

Superlattice (SL) GaAs



SL – GaAs with Bragg Reflector

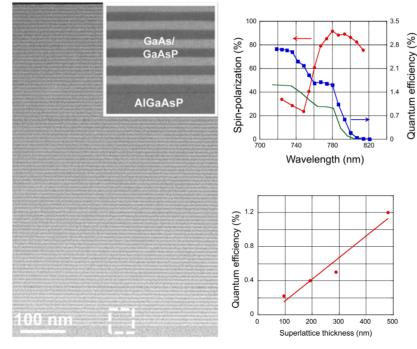


Brookhaven National Laboratory Jin et el. Appl. Phys. Lett. 105, 203509 (2014)

Superlattice (SL) GaAs

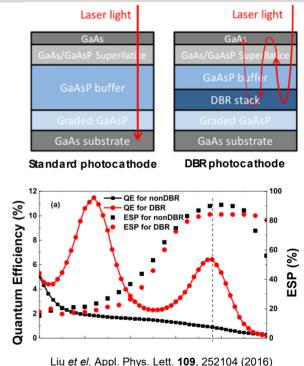
Brookhaven

National Laboratory



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SL – GaAs with Bragg Reflector



25

Motivation:



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□ We need stable vendors.



We have been growing SL-DBR and characterizing them ➤ Details will follow in the Poster session: **WEPA68**

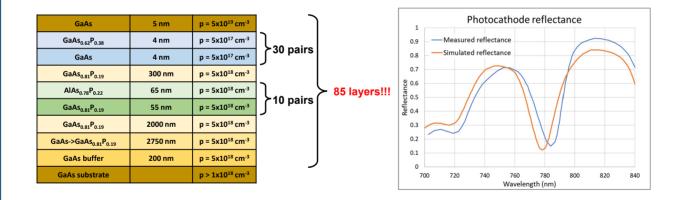


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GaAs	5 nm	p = 5x10 ¹⁹ cm ⁻³	
GaAs _{0.62} P _{0.38}	4 nm	p = 5x10 ¹⁷ cm ⁻³	
GaAs	4 nm	p = 5x10 ¹⁷ cm ⁻³	S30 pairs
GaAs _{0.81} P _{0.19}	300 nm	p = 5x10 ¹⁸ cm ⁻³	
AIAs _{0.78} P _{0.22}	65 nm	p = 5x10 ¹⁸ cm ⁻³	3 85 layers!!!
GaAs _{0.81} P _{0.19}	55 nm	p = 5x10 ¹⁸ cm ⁻³	}10 pairs
GaAs _{0.81} P _{0.19}	2000 nm	p = 5x10 ¹⁸ cm ⁻³	
GaAs->GaAs _{0.81} P _{0.19}	2750 nm	p = 5x10 ¹⁸ cm ⁻³	
GaAs buffer	200 nm	p = 5x10 ¹⁸ cm ⁻³] J
GaAs substrate		p > 1x10 ¹⁸ cm ⁻³	



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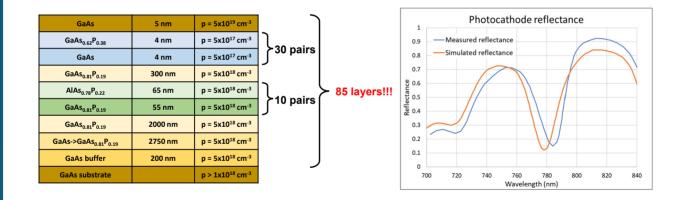


Good agreement between the design reflectance and the measured one.

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Achieved over 15% QE and ESP around 75% at near band gap photon energies.



J. Biswas et el. NAPAC 2022, Paper WEPA68



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 - Let's evaluate the robustness & charge lifetime of Cs-Te-O/GaAs in a gun



SL / SL-DBR with Cs-Te-O based activation



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- On SL-DBR we obtained QE exceeding 15% and ESP around 75% at near bandgap photon energy (i.e., ~780 nm)
 - Further tuning of SL layer, and growth method are ongoing, and activation with Cs-Te-O could lead to even higher QE.



Thanks for your attentions!

Acknowledge: L. Cultrera, E. Wang, W. Liu, O. Rahman, M. Gaowei, J. Skaritka, X. Tong, J. Sadowski, K. Kisslinger, I. Ben-Zvi, T. Rao, S.D. Hawkins, S.R. Lee, J.F. Klem.

